# TRANSFER DEVICE AND GAS SUPPLY METHOD


## ABSTRACT

A transfer device for loading and unloading substrates into and from a processing apparatus configured to process the substrates, includes: a main body including a transfer space in which a transfer robot configured to transfer the substrates is provided, and a storage space connected to the transfer space and configured to support the substrates. The main body includes: a first fan filter unit arranged above the transfer space and configured to blow a gas supplied to the transfer space; a second fan filter unit provided separately from the first fan filter unit and configured to blow a gas supplied to the storage space; a gas supply passage configured to supply the gas blown from the second fan filter unit to the storage space; and an exhaust passage configured to exhaust the gas supplied to the storage space.

(Fig. 6)